TECHNICAL SPEC FOR Ion Implanter

System Model:
Axcelis 6200AV

- **Wafer size? 6 inch**
- **Wheel type? none**
- **Wafer tilt? 0/45**
- **Source (i.e. Bernas or IHC)? bernas**
- **Extraction system (i.e. dual bellows)? fixed**
- **Gases? Boron, phosfine**
- **SDS Gas box? yes**
- **Max implantation energy (in KeV)? 180**
- **Max Extraction voltage (in KeV)? 20**
- **Heat Exchanger? no**

- **Orienter type (flat, notced, etc…)? flat**
- **Hydrogen implantation available? no**
- **Number of trays? 1**
- **Load and unload locks: yes**
- **Source extraction alignment jig yes**
- **AMU yes**
- **Beamline column yes**
- **Mechanical clamp: yes**
- **Turbo type? none**
- **PC type:**
- **Cryo type? cti**
- **PFS standard or HD? hd**